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(54) **Grating and method of providing a grating in an ion diffused waveguide**

(57) A method of forming a grating in waveguide uses an ion exchange process to provide a waveguide region within and clad by a surrounding substrate and through an ion exchange process diffusing into the substrate an ion, such as such as Ag⁺ that is photosensitive and that provides a refractive index difference from adjacent non-diffused regions of the substrate. After the diffusion process, the step of exposing at least some of the waveguide region to light having a suitable intensity and duration to provide a permanent index change within regions of the waveguide region to form a grating is performed.

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Description

Field of the Invention

[0001] This invention relates generally to producing optical waveguides by ion exchange having a grating impressed therein.

Background of the Invention

[0002] Interest in the use of ion-exchanged glass waveguides for integrated optics has increased considerably recently. Since the operation of optical glass waveguides is passive and does not allow adjustment after production. To produce optical fiber compatible waveguide devices by an ion exchange technique, two-step processes are generally used. In these processes, waveguide are formed by the exchange of the original ions in the glass (typically sodium ions Na⁺) to ions increasing the refractive index (such as K⁺, Ag⁺, Cs⁺, Rb⁺, Li⁺ or Tl⁺ ions) through a narrow opening in the ion exchange mask, and by using salt melts or a silver film as an ion source. In the second step, thermal treatment or ion exchange in an NaNO₃ melt modifies the refractive index profile of the waveguide to obtain better coupling to an optical fibre. A description of the basic principles of ion exchange are found in an article entitled *Ion-Exchanged Glass Waveguides: A Review*, R.V. Ramaswamy, *Journal of Lightwave Technology*, Vol. 6, No. 6, Jun. 1988, P. 984.

[0003] An early teaching of making waveguides in a substrate is found in United States Patent 4,793,675 in the name of Handa, assigned to Canon Kabushiki Kaisha of Japan. Handa discloses a method of making a element having a light waveguide in which the input-output area through which light is input or output is made into a light waveguide of a high threshold value of optical damage formed by outside diffusion of lithium oxide or by ion exchange.

[0004] Further work in the field of producing optical waveguides by ion exchange on a glass substrate can be found in United States Patent 5,160,523 in the name of Honkanen et al. assigned to Oy Nokia AB, of Helsinki Finland, issued November 3, 1992. In this disclosure, in order to alleviate the tolerances allowed for the ion exchange technique, the waveguides are formed in the invention by diffusing ions which increase the refractive index away from a waveguide formed previously on the glass substrate and being wider than the optical waveguides to be produced by using the ion exchange technique and a positive type ion exchange mask.

[0005] As with optical fibres, there is increasing interest in fabricating devices within a monolithic block of glass, comprising optical waveguides; however this has continued to be difficult. A process has recently been disclosed by Nippon Sheet Glass Co., Ltd. of Japan that relates to fabricating of a grating on glass using laser machining. A diffusion process is first per-

formed wherein molten salt comprising AgNO₃+NaNO₃, is diffused at a temperature of 300 degrees Celsius for a duration ranging from 1 minute to 80 hours in air. Laser machining is later performed using a phase mask to etch a grating within the material. Laser ablation results in regions wherein the waveguide material is etched away creating index differences between ablated regions consisting of air, and the adjacent unablated material interfaces.

[0006] In accordance with one aspect of this invention, a method is described of providing a grating within a monolithic waveguide, by first performing an ion exchange process, wherein, for example Na⁺ ions are exchanged with Ag⁺ ions to provide a waveguide within glass or another substrate material. According to known techniques of writing or impressing optical gratings in germanium doped optical fibre, as are described in United States Patents 5,327,515, 5,104,209, 5,216,739, 4,725,110, and, 4,800,950 we have discovered that a grating can be impressed by, for example interfering two beams within the Ag⁺ ion exchanged waveguide.

[0007] In a preferred embodiment, prior to the ion exchange process, the material to be used is comprised as follows:

Compound	Mol%	Gw%
SiO ₂	62.90	56.54
B ₂ O ₃	12.00	12.50
Na ₂ O	12.50	11.57
Al ₂ O ₃	12.50	19.06
As ₂ O ₃	0.10	0.29
F-	6.30	4.56

[0008] In accordance with a broad aspect of the invention, permanent refractive index changes in the form of a Bragg grating is provided Within a substrate having an ion diffused waveguide formed therein. The waveguide comprises a material, i.e. Ag⁺ that is photosensitive. The diffused ion in the preferred embodiment is Ag⁺ however other photosensitive ions may be used. Preferably, the Bragg grating is formed by interfering two light beams within the waveguide region using known techniques. Heretofore, the writing of such a grating has been performed in an optical fibre having a germanium doped light sensitive core.

[0009] Heretofore, providing a grating in an ion-diffused waveguide has been a complex process of etching or ablating the portions of the waveguide region with a high power laser.

Claims

1. A method of forming a grating in waveguide, comprising the steps of:

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using an ion exchange process to provide a waveguide region within and clad by a surrounding substrate and through an ion exchange process diffusing into the substrate an ion that is photosensitive and that provides a refractive index difference from adjacent non-diffused regions of the substrate;

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exposing at least some of the waveguide region to light having a suitable intensity and duration to provide a permanent index change within regions of the waveguide region to form a grating.

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2. A method of forming a grating in waveguide, comprising the steps of:

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providing an ion diffused waveguide region within a substrate;

exposing the ion diffused waveguide region to light by interfering two beams within the ion diffused waveguide region.

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3. A method as defined in claim 1 or 2 wherein the ion diffused within the substrate to form the waveguide region is Ag+.

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4. A method as defined in claim 1, wherein a mask is used between a light source and the substrate.

5. A method as defined in claim 4, wherein the mask is a phase mask for splitting a beam incident thereon into a plurality of beams.

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6. A method as defined in claim 5, wherein at least two of the plurality of beams are interfered within the waveguide region.

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EUROPEAN SEARCH REPORT

Application Number
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DOCUMENTS CONSIDERED TO BE RELEVANT			
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The present search report has been drawn up for all claims			
Place of search THE HAGUE		Date of completion of the search 28 April 1999	Examiner Mathyssek, K
<p>CATEGORY OF CITED DOCUMENTS</p> <p>X : particularly relevant if taken alone Y : particularly relevant if combined with another document of the same category A : technological background O : non-written disclosure P : intermediate document</p> <p>T : theory or principle underlying the invention E : earlier patent document, but published on, or after the filing date D : document cited in the application L : document cited for other reasons</p> <p>A : member of the same patent family, corresponding document</p>			

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**ANNEX TO THE EUROPEAN SEARCH REPORT
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This annex lists the patent family members relating to the patent documents cited in the above-mentioned European search report.
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For more details about this annex : see Official Journal of the European Patent Office, No. 12/82